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***Cubic Crystalline Erbium Oxide Growth on GaN(0001)
by Atomic Layer Deposition—Supplement 1***

UT Dallas Author(s):

Sunah Kwon
Qingxiao Wang
Moon J. Kim

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Supplementary Material

Cubic Crystalline Erbium Oxide Growth on GaN(0001) by Atomic Layer Deposition

Pei-Yu Chen,¹ Agham B. Posadas,² Sunah Kwon,³ Qingxiao Wang,³ Moon J. Kim,³ Alexander A. Demkov,² John G. Ekerdt¹

¹Department of Chemical Engineering, The University of Texas at Austin, Austin, Texas 78712, USA

²Department of Physics, The University of Texas at Austin, Austin, Texas 78712, USA

³Department of Materials Science and Engineering, The University of Texas at Dallas, Richardson, Texas 75080, USA

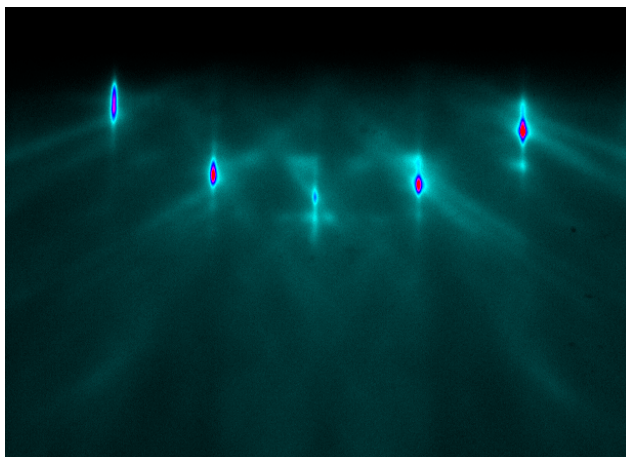


FIG. S1. RHEED image of GaN substrate cleaned by chemicals (acetone, isopropyl alcohol, deionized water, HCl, and NH₄OH in sequence) and N₂ plasma. The image shows a 1×1 surface along the <11-20> azimuth.

Supplementary Calculation I:

Theoretical lattice mismatch between a cubic structure and a wurtzite structure can be calculated by finding the matching surface unit cells at a superlattice distance.¹ For the C-Er₂O₃/GaN heterostructure, the GaN(0001) and C-Er₂O₃(111) planes are aligned from XRD measurements (Fig. 3) and this alignment leads to $\sqrt{2} \times a_{Er_2O_3}$ ($a_{Er_2O_3} = 10.547 \text{ \AA}$) as the in-plane $a_{IP-Er_2O_3}$. A superlattice with five times the GaN lattice constant ($a_{GaN} = 3.189 \text{ \AA}$) is found to match $a_{IP-Er_2O_3}$ the best. Using five times the GaN lattice constant leads to a lattice mismatch of +6.90% as shown below.

$$Mismatch = \frac{3.189 \times 5 - \sqrt{2} \times 10.547}{\sqrt{2} \times 10.547} \times 100\% = 6.90\%$$

The corresponding crystal structure viewed along C-Er₂O₃<111> || GaN<0001> is also simulated by VESTA² to examine the lattice mismatch between C-Er₂O₃ and GaN, as shown in Fig. 8. The lattice mismatch along GaN<11-20> and GaN<1-100> directions are estimated as follows.

Along GaN<11-20>:

$$d_{Ga-Ga} = 3.189 \text{ \AA}$$
$$d_{Er_2O_3(-220)} = 3.729 \text{ \AA}$$

From Fig. 8, coincidence of Er atoms with Ga atoms along the GaN<11-20> direction leads to $5 \times \overline{Ga-Ga} \cong 4 \times \overline{Er-Er}$. Therefore, five times of d_{Ga-Ga} is used to compare with four times of $d_{Er_2O_3(-220)}$, which results in the lattice mismatch of +6.90%.

$$Mismatch = \frac{3.189 \times 5 - 3.729 \times 4}{3.729 \times 4} \times 100\% = 6.90\%$$

Along GaN<1-100>:

$$d_{Ga-Ga} = 5.524 \text{ \AA}$$
$$d_{Er_2O_3(-422)} = 2.153 \text{ \AA}$$

From Fig. 8, coincidence of Er atoms with Ga atoms along the GaN<1-100> direction leads to $3 \times \overline{Ga-Ga} \cong 7 \times \overline{Er-Er}$. Similarly, the lattice mismatch of +9.96% is obtained by using three times of d_{Ga-Ga} and seven times of $d_{Er_2O_3(-422)}$.

$$Mismatch = \frac{5.524 \times 3 - 2.153 \times 7}{2.153 \times 7} \times 100\% = 9.96\%$$

Supplementary Calculation II:

The lattice mismatch at various temperatures can be estimated by utilizing the coefficient of thermal expansion, α . The thermal expansion coefficients for Er_2O_3 and GaN are $7.25 \times 10^{-6} \text{ K}^{-1}$ and $5.59 \times 10^{-6} \text{ K}^{-1}$, respectively.³⁻⁴ With $\left(\frac{\Delta L}{L}\right) = \alpha \Delta T$ and five times the multiple of the GaN, lattice constants and lattice mismatch can be calculated at the 250 °C ALD growth temperature and the 600 °C post-deposition annealing temperature.

At room temperature of 25 °C:

$$\text{Mismatch} = \frac{3.189 \times 5 - \sqrt{2} \times 10.547}{\sqrt{2} \times 10.547} \times 100\% = 6.90\%$$

At the deposition temperature of 250 °C:

$$\begin{aligned} L_{\text{GaN}} &= 5.59 \times 10^{-6} \times (250 - 25) \times 3.189 + 3.189 = 3.193 \\ L_{\text{Er}_2\text{O}_3} &= 7.25 \times 10^{-6} \times (250 - 25) \times 10.547 + 10.547 = 10.564 \\ \text{Mismatch} &= \frac{3.193 \times 5 - \sqrt{2} \times 10.564}{\sqrt{2} \times 10.564} \times 100\% = 6.86\% \end{aligned}$$

At the post-deposition annealing temperature of 600 °C:

$$\begin{aligned} L_{\text{GaN}} &= 5.59 \times 10^{-6} \times (600 - 25) \times 3.189 + 3.189 = 3.199 \\ L_{\text{Er}_2\text{O}_3} &= 7.25 \times 10^{-6} \times (600 - 25) \times 10.547 + 10.547 = 10.591 \\ \text{Mismatch} &= \frac{3.199 \times 5 - \sqrt{2} \times 10.591}{\sqrt{2} \times 10.591} \times 100\% = 6.79\% \end{aligned}$$

The differences in lattice mismatch at various temperatures are small due to the similar coefficients of thermal expansion for Er_2O_3 and GaN. Therefore, thermal expansion is a minor contributing factor for introducing tensile strain into C- Er_2O_3 during cooling from the growth temperature and the annealing temperature to room temperature.

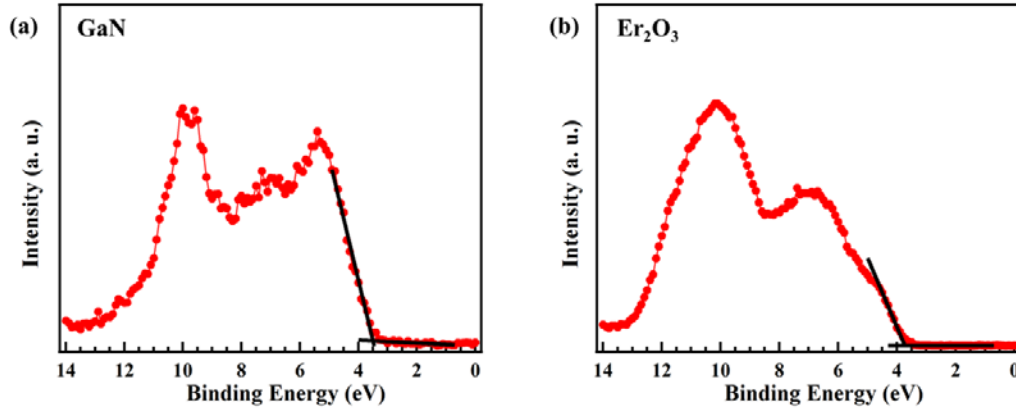


FIG. S2. The valence band spectra of (a) the clean GaN(0001) surface and (b) the 19.6-nm thick Er_2O_3 film. The VBM value is determined by extrapolating the leading edge of the valence band spectrum to the base line. The clean GaN shows a VBM binding energy of 3.50 eV, while 19.6-nm thick C- Er_2O_3 displays a VBM binding energy of 3.73 eV.

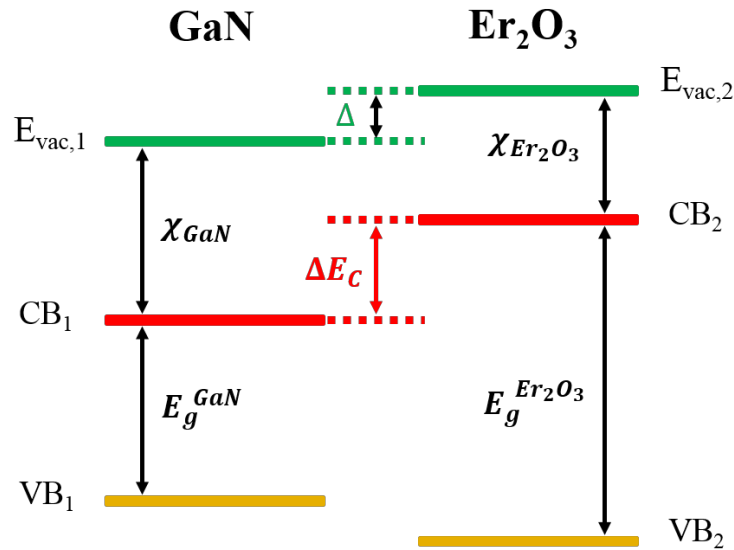


FIG. S3. The band diagram affected by the interface dipole (Δ). In this scenario the ΔE_C is increased by the presence of the positive interfacial dipole.

Supplementary Material References

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